

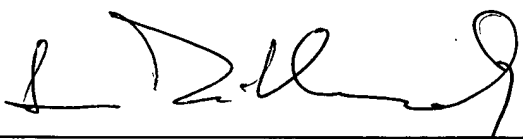
218); a detection system (212) for detecting light from the wafer; a data processing system (213) for collecting and analyzing the data received by the detection system.

However, the amended claim 62 is directed to a wide field of view scanner for delivering excitation light and detecting excited fluorescent light. The scanner includes a scanning assembly for **displacing an objective lens in a scanning motion**, while the optical path provided by the displaced objective lens and the scanning assembly has a substantially constant length. There are fundamental differences between this invention and the teaching of Worster. Worster does not disclose a scanner for delivering excitation light and detecting the excited fluorescent light. Worster does not disclose a scanner with a scanning assembly for displacing an objective lens in a scanning motion. Worster teaches a stationary objective lens during scanning (after the appropriate lens was selected from several lenses mounted on a turret); that is, during the scanning process the lens is stationary and the substrate is displaced using a moving stage.

Accordingly, all pending claims 62 through 90 are in condition for allowance and such action is respectfully requested.

Please charge all US PTO fees, including claim fees, and apply any credits to the Deposit Account No. 01-0431.

Respectfully submitted,


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|------------|---|-----------------------|
| Applicant: | James W. Overbeck . | Examiner: T.Q. Nguyen |
| Serial No: | 10/034,620 | Art Unit: 2872 |
| Filed: | December 27, 2001 | |
| For: | WIDE FIELD OF VIEW AND HIGH SPEED SCANNING MICROSCOPY | |

AMENDMENTS
with changes shown

62. (Amended) A wide field of view scanner, comprising:

- a scanning assembly constructed to provide a light excitation beam emitted from a light source in a scanning motion to an examined surface;
- an objective lens associated with and displaced by said [the] scanning assembly arranged to provide an optical path from said light source to the examined surface and from the examined surface fluorescent light, excited in response to said excitation beam, to a light detector; said displaced objective lens and said scanning assembly providing said optical path having substantially constant length;
- a translation system constructed to produce movement of the examined surface;
- and
- a data collection control and processing unit arranged to collect data during the scanning motion and process the collected data.